

SEMICONDUCTOR MANUFACTURING PLANT

ABSTRACT

A fluorine gas generator is connected with semiconductor production units (3a-3e) through a gas supply system (2) having a tank (12) for storing a predetermined amount of fluorine gas generated from on-site fluorine gas generators (1a-1e). When one or more of the on-site fluorine gas generators (1a-1e) stop, fluorine gas is supplied from the storage tank (12) storing a predetermined amount of fluorine gas to the semiconductor production units (3a-3e) thus sustaining operation of the semiconductor production units (3a-3e). Consequently, fluorine gas generated from the fluorine gas generator can be supplied to the semiconductor production unit safely and stably, and a semiconductor production plant exhibiting excellent cost performance in semiconductor production can be attained.

Fig. 1